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PATENT APPLICATION

AF 2813
#14
Dswgo
SP Davis
11/14/03

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

ATSUSHI KOIKE ET AL.

Application No.: 09/982,846

Filed: October 22, 2001

For: METHOD FOR FORMING
A DEPOSITED FILM BY
PLASMA CHEMICAL VAPOR
DEPOSITION

Examiner: E.J. Kielin

Group Art Unit: 2813

October 23, 2003

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

TRANSMITTAL OF AMENDED DRAWINGS

Sir:

Pursuant to the request in the Office Action dated September 23, 2003, replacement figures have been enclosed herewith which incorporate the approved drawing corrections filed June 23, 2003 in paper No. 11. These corrections comprise adding numeral 106 to Figures 1 and 14. It is requested that the amended drawings be accepted by the Examiner.

RECEIVED
OCT 28 2003
TECHNOLOGY CENTER 2800

Applicants' undersigned attorney may be reached in our New York office by telephone at (212) 218-2100. All correspondence should continue to be directed to our address given below.

Respectfully submitted,



Attorney for Applicants

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